

Form PTO-1449

Docket Number (Optional)

Application Number

CS-01-193

10/697,746

Applicant

Tze Ho Chan et al.

Filing Date

10/30/03

Group Art Unit

INFORMATION DISCLOSURE CITATION  
IN AN APPLICATION

(Use several sheets if necessary)

## U. S. PATENT DOCUMENTS

EXAMINER PAGE INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILED DATE IF APPROPRIATE
on	6358819	3/19/02	Shelton et al.	438	433	12/15/98
on	5918116	6/29/99	Chittipeddi	438	199	5/9/97
on	6063670	5/16/00	Lin et al.	438	275	4/15/98
on	6342438	1/29/02	Yu et al.	438	520	11/6/98
on	5356821	10/18/94	Naruse et al.	437	34	8/12/93
on	6376323	4/23/02	Kim et al.	438	373	4/4/01

## FOREIGN PATENT DOCUMENTS

DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
					YES	NO

## OTHER DOCUMENTS (Including Author, Title, Date, Portion of Pages, Etc.)

on	CS-01-093	Serial No. 10/266,425, Filed 10/08/02 to
		Chew-Hoe Ang et al., "Dual Si-Ge Polysilicon
on		Gate with Different Ge Concentrations for
		CMOS Device Optimization"

EXAMINER

DATE CONSIDERED



11-24-04

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.